

AM Session

8:30	REGISTRATION
9:00	National Anthem
	Opening Prayer
	Welcome Remarks (CFAR / KFI / DLSU)
9:15	"Overview of EFA Technologies for Die-Level Analysis, from Optical Fault
	Isolation to Nano-Probing" By Dr. Chun-Cheng Tsao,

10:00 Coffee Break

- 10:15"ELITE, Lock-In Thermography Solution for Non-Destructive and Z-DepthAnalysis" By David Tien
- 11:30 Possibilities in Imaging & Analysis: PhenomWorld

12 noon Lunch Break

PM Session

- 1:00 CFAR
- 1:30 Industrial Application by Atomic Force Microscopy (AFM) Steve Ong, PhD, Park Systems
- 2:30 Introduction of the Solid State Sample Preparation Workflow Ms. Angela Hu, MS MSE, Leica Microsystems

3:00 Coffee Break

3:15 Break Out Sessions: Workshop/Demo with FEI, PhenomWorld, Park Systems, EDAX, Leica Microsystems

5:00 End of Session